

Notice of References Cited

Application/Control No.

09/732,712

Applicant(s)/Patent Under
Reexamination
ITOU ET AL.

Examiner

Yelena G. Gakh, Ph.D.

Art Unit

1743

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-4,023,193	05-1977	Schroter et al.	396/564
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Wu et al. "Quantitative Analysis of Trace Moisture in NH3 Gas with Dual-Cell Near-Infrared Diode Laser Absorption Spectroscopy", Anal. Chem., 1998, v. 70, pp. 3315-3321
	V	Wu et al. "Absorption Spectrometry of Trace Moisture in Ammonia Gas with a 1371 nm Distributed-Feedback Diode Laser", Jap. J. Appl. Phys., 1999, 38(8), 4788-4793
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	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.